

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 292628US0PCT		SERIAL NO. 10/583,719	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Claire DIVOUX, et al.		GROUP 1713	
				FILING DATE June 20, 2006			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	4 203 128	05/13/1980	GUCKEL et al.			
	AB	6 369 931	04/09/2002	FUNK et al.			
	AC	6 577 427	06/10/2003	GEE et al.			
	AD	5 629 790	05/13/1997	NEUKERMANS et al.			
	AE	6 563 106	05/13/2003	BOWERS et al.			
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AO	01 92939	12/06/2001	WO (equivalent of US 2003 019832 and US 2002 008922)			NO
	AP	1 338 912	08/27/2003	EP (equivalent of US 2002 118429)			NO
	AQ	01 53872	07/26/2001	WO (equivalent of US 2003 203530 and US 2001 044165)			NO
	AR						
	AS						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AT	BIFANO et al., "CONTINUOUS-MEMBRANE SURFACE-MICROMACHINED SILICON DEFORMABLE MIRROR", SOCIETY OF PHOTO-OPTICAL INSTRUMENTATION ENGINEERS, Vol. 36, No. 5, pages 1354-1359, 1997 May 1997					
	AU	HAMMER et al., "DESIGN AND FABRICATION OF A CONTINUOUS MEMBRANE DEFORMABLE MIRROR", PROCEEDINGS OF SPIE, Vol. 4983, pages 259-270, 2003 no month available					
	AV	ROBERT et al., "LEMICRO MIRROR ADAPTATIF: UN MICRO COMPOSANT D'OPTIQUE ADAPTATIVE", SECOND FORUM ADEMIS, pages 161-165, 1997 no month available					
	AW	DIVOUX et al., "A NOVEL ELECTROSTATIC ACTUATOR FOR MICRO DEFORMABLE MIRRORS: FABRICATION AND TEST", TRANSDUCERS, SOLID-STATE SENSORS, ACTUATORS AND MICROSYSTEMS, 12 <sup>TH</sup> INTERNATIONAL CONFERENCE HELD ON 2003, Vol. 1, pages 488-491, 2003 no month available					
	AX	KRISHNAMOORTHY et al., "STATISTICAL PERFORMANCE EVALUATION OF ELECTROSTATIC MICRO ACTUATORS FOR A DEFORMABLE MIRROR", SPIE, Vol. 2881, pages 35-44, 1992 no month available					
	AY	YANG et al., "CONCEPT, MODELING AND FABRICATION TECHNIQUES FOR LARGE-STROKE PIEZOELECTRIC UNIMORPH DEFORMABLE MIRRORS", PROCEEDINGS OF SPIE, Vol. 4983, pages 271-278, 2003 no month available					
	AZ	YANG et al., "A NEW WAFER-LEVEL MEMBRANE TRANSFER TECHNIQUE FOR MEMS DEFORMABLE MIRRORS", 2001 no month available				<input type="checkbox"/> Additional References sheet(s) attached	
Examiner		/Anita Alanko/ (05/06/2010)					
		Date Considered					

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /A.A./ (05/06/2010)

	Docket No.: 292628US0PCT	Serial No.: 10/583,719
LIST OF RELATED CASES CITED BY APPLICANT UNDER 37 CFR 1.56	Inventor: Claire DIVOUX, et al.	
	Filing Date: June 20, 2006	Group:

**LIST OF RELATED CASES**

<u>Examiner Initial</u>	<u>Docket No.</u>	<u>Serial or Patent Number</u>	<u>Filing or Issue Date</u>	<u>Patent App. Publication No.</u>	<u>Inventor or Applicant</u>
	292627US2XPCT	10/583,718	06/20/06		CHARTON et al.
	292962US2	11/472,377	06/22/06		CHAPPAZ et al.
	292748US2PCT	10/584,202	06/23/06		DIVOUX
	<del>292628US0PCT</del>	<del>10/583,719</del>	<del>06/20/06</del>		<del>DIVOUX et al.</del>

Examiner /Anita Alanko/ (05/06/2010)

Date Considered

\*Present Application; listed for information

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